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Narsapur, West Godavari District, A.P. 534280

DEPARTMENT OF MECHANICAL ENGINEERING

LESSON PLAN

		Course Title	Semester		Branches	Contact Periods /Week	Academ ic Year	Date of commencement of Semester		
20RB7E11 Mechanical Systems					5	2025-26	09-06-2024			
COUF	RSE OUT	COMES						×		
1	Classify various micro electro mechanical system components.[K2]									
2	Demonstrate mechanical sensors and actuators.[K2]									
3	Describe thermal sensors and actuators.[K2]									
4	Describe magnetic sensors and actuators. [K2]									
5	Illustrate micro-opto-electro mechanical systems. [K2]									
UNIT	Bloom's Level		Topi cs No.		Topics/Activity		Text Book / Referen ce	Cont act Hou r	Delivery Method	
				IN	FRODUCTION	Ţ				
	Classify various		1.1	136 150 15W	iction about Mic	ro Electro	T1, T2	1		
			1.2	MEMS	history and dev	elopment	T1, T2	1		
			1.3	Micro	Machining		T1, T2	1		
			1.4	Lithog	raphy Principles	Principles & Methods		1	Chalk & Talk,	
I	micro electro mechanical system components. [K2]	1.5	Structu	ral and Sacrifici	al Materials	T1, T2	1	PPT &		
		1.6	Thin F	ilm Deposition	(81)	T1, T2	1 Think share			
		1.7	Impuri	ty Doping & Etc	hing	T1, T2	1	Pair		
		1.8	Surface	Micro machini	ng	T1, T2	1			
			1.9	Wafer	Bonding		T1, T2			
			1.10	IGA	T1, T2			1		
				Total				10		



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	ME	CHAN	ICAL SENSORS AND ACTUATO	ORS		
II	Demonstrate mechanical sensors	2.1	Principles of sensing and actuation: beam and cantilever	T1, R1	1	
		2.2	Capacitive sensor	T1, R1	1	
		2.3	Piezo electric sensor	T1, R1	1	
		2.4	Strain sensor, pressure & flow sensor	T1, R1	1	Chalk & Talk, & Video
		2.5	Pressure measurement by micro phone	T1, R1	1	
	and actuators. [K2]	2.6	MEMS gyroscope	T1, R1	1	
		2.7	Shear mode piezo actuator	T1, R1	1	
		2.8	Gripping piezo actuator	T1, R1	1	
		2.9	Inchworm technology	T1, R1	1	
			Total		09	
	T	HERM	IAL SENSORS AND ACTUATOR	S		
		3.1	Heat transfer processes	T1,T3	1	Chalk & Talk, & Video
	Describe thermal sensors and actuators. [K2]	3.2	Thermistors & Thermos devices	T1,T3	1	
		3.3	Thermocouple	T1,T3	1	
		3.4	Micro machining	T1,T3	1	
		3.5	Peltier effect heat pumps	T1,T3	1	
TTT		3.6	Thermal flow sensors	T1,T3	1	
III		3.7	Micro hot plate gas sensors	T1,T3	1	
		3.8	Shape memory alloys	T1,T3	1	
		3.9	U shaped horizontal and vertical electro thermal sensor	T1,T3	1	
		3.10	Micro spring thermal actuator	T1,T3	1	
		3.11	Data storage cantilever	T1,T3	1	1
			Total		11	A
	M	IAGNE	TIC SENSORS AND ACTUATOR	RS		
		4.1	Magnetic sensing and detection	T1,R1	1	
		4.2	Magneto resesitive sensors	T1,R1	1	
		4.3	Halls effect	T1,R1	1	



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		4.4	Magneto diodes & transistor	T1,R1	1	
IV	Describe magnetic sensors and actuators. [K2]	4.5	MEMS magnetic sensor	T1,R1	1	Chalk & Talk, - & Quiz
		4.6	Pressure sensor	T1,R1	1	
		4.7	Magnetic MEMS actuator	T1,R1	1	
		4.8	Directional micro actuator	T1,R1	1	
		4.9	Feedback circuit integrated magnetic sensor	T1,R1	1	
Cour	se Beyond Syllabus		Chemical and Biological sensors	T1	1	
	10					
	MICRO-OPTO-	ELEC	TRO MECHANICAL SYSTEMS			
		5.1	Principle of MOMS technology	T1,T2	1	
	Illustrate micro- opto-electro mechanical systems [K2]	5.2	Properties of light & Light modulators	T1,T2	1	
		5.3	Beam splitter	T1,T2	1	1 Chalk & Talk, 1 & Video 1 1 1 1 1 1 1 1 1 1 1 1 1 1 1 1 1 1 1
		5.4	Micro lens & Micro mirrors	T1,T2	1	
V		5.5	Digital micro mirror device	T1,T2	1	
		5.6	Light detectors	T1,T2	1	
		5.7	Grating light valve and optical switch,	T1,T2	1	
		5.8	Wave guide and tuning	T1,T2	1	
		5.9	Shear stress measurement	T1,T2	1	
Cour	se Beyond Syllabus		Microfluidic Devices	T1	1	
			Total		10	
			CUMULATIVE PROPOSED P	ERIODS	50	
Text E	Books:					
S.No.	AUTHORS, BOOK	TITL	E, EDITION, PUBLISHER, YEAR	OF PUBL	ICAT	ION
T1	Mahalik N P, MEMS, Tata McGraw-Hill Education (India) Pvt Limited, 2013.					
T2	Rai - Choudhury P, MEMS and MOEMS Technology and Applications, PHI Learning Private Limited, 2009.					
T3	Nadim Maluf, An Introduction to Micro Electro Mechanical System Design,2 nd Edition, Artech House, 2004.					



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Refere	rence Books:						
S.No.	AUTHORS, BOOK TITLE, EDITION, PUBLISHER, YEAR OF PUBLICATION						
R1	Tai-Ran Hsu, MEMS and Micro Systems: Design and Manufacture, 1st Edition, McGraw Hill						
	Education, 2017						
R2	Chang Liu, Foundation of MEMS, 2 nd Edition, Pearson Education, 2011						
R3	Gerald Urban, Bio-MEMS (Micro systems), Springer.2006						
R4	Mohamed Gad-el-Hak, MEMS Handbook, CRC Press, 2002.						
Web D	Details						
	https://nptel.ac.in/courses/117105082						
	https://lecturenotes.in/subject/134/micro-electro-mechanical-systems						
	Name Signature w	vith Date					

		Name	Signature with Date
i.	Faculty	Dr. R Sanjeev Kumar	255
ii.	Course Coordinator	Dr. R Sanjeev Kumar	35]
iii.	Module Coordinator	Dr. D Bhanu Prakash	D. Rohne hund
iv.	Programme Coordinator	Dr. M Francis Luther King	Shylmtog.

Principal